Title: LOADING DEVICE FOR CHEMICAL MECHANICAL POLISHER OF SEMICONDUCTOR WAFER

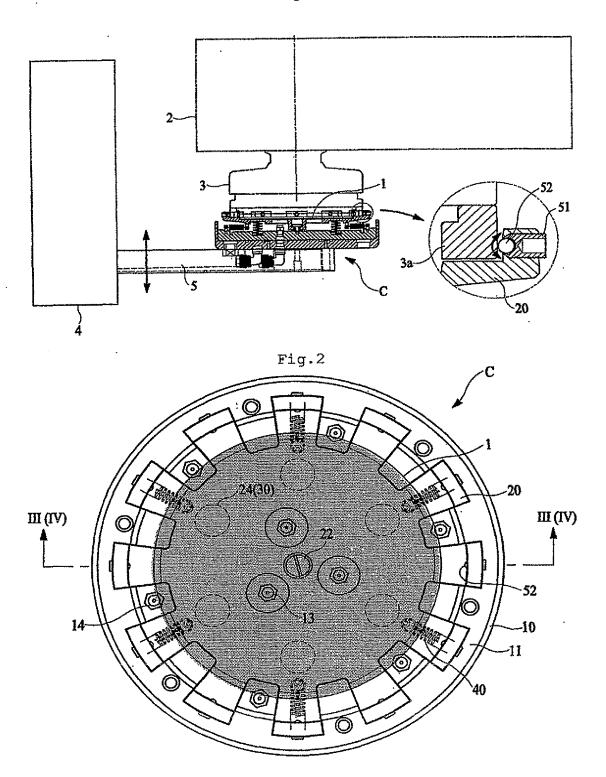
Inventors: Jung Hoon LEE
Atty Docket No.: 403835
Leydig, Voit & Mayer 202-737-6770

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Fig.1



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Fig.3

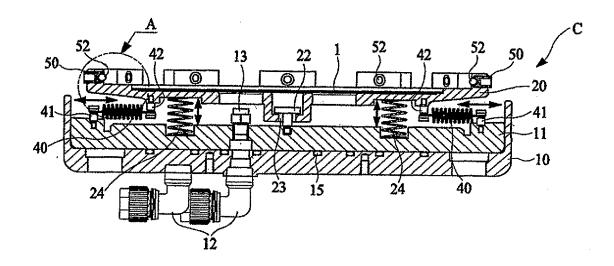
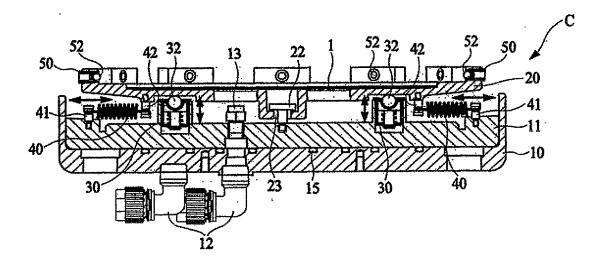


Fig.4



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Fig.5

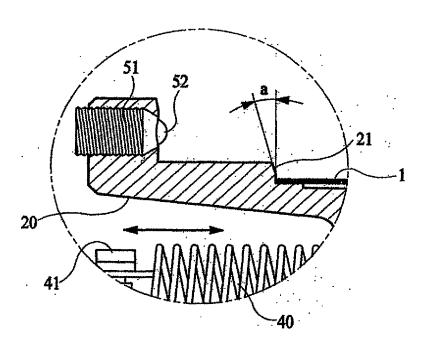
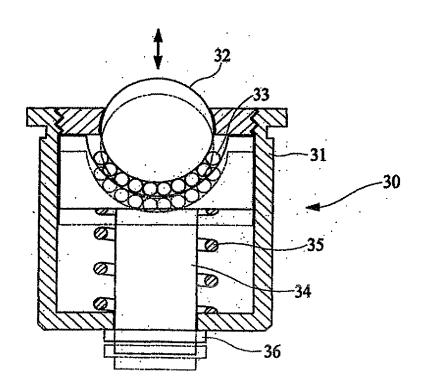


Fig.6



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Fig.7

